

Application Data Sheet

Application Information

Application number::

Filing Date::

Application Type::

Regular

Subject Matter::

Utility

Title ::

LASER IRRADIATION
APPARATUS, LASER
IRRADIATION METHOD,
AND METHOD FOR
MANUFACTURING A
SEMICONDUCTOR DEVICE

Attorney Docket Number:: 0756-7223

Total Drawing Sheets:: 8

Small Entity?:: No

Applicant Information

Applicant Authority Type:: Inventor

Primary Citizenship Country:: Japan

Given Name:: Koichiro

Middle Name::

Family Name:: TANAKA

Name Suffix::

City of Residence:: Atsugi

State or Province of Residence:: Kanagawa

Country of Residence:: Japan

Street of mailing address:: c/o Semiconductor Energy
Laboratory Co., Ltd.
398, Hase
Atsugi-shi
State or Province of mailing address:: Kanagawa-ken
Country of mailing address:: Japan
Postal or Zip Code of mailing address:: 243-0036

Correspondence Information

Correspondence Customer Number :: 31780
E-Mail address:: erobinson@riplo.com

Representative Information

Representative Customer Number:: 31780

Domestic Priority Information

Application ::	Continuity Type::	Parent Application::	Parent Filing Date::

Foreign Priority Information

Country::	Application number::	Filing Date::	Priority Claimed::
Japan	2002-349007	11/29/2002	Yes

Assignee Information

Assignee name:: Semiconductor Energy
Laboratory Co., Ltd.

Street of mailing address:: 398 Hase

City of mailing address:: Atsugi-shi

State or Province of mailing address:: Kangawa-ken

Country of mailing address:: Japan

Postal or Zip Code of mailing address:: 243-0036